

1746 Sall

TRANSMITTAL OF FORMAL DRAWINGS

Docket No.  
FIS920000409US1

In Re Application Of: MICHAEL R. SIEVERS, ET AL.

4-8-02

Serial No.	Filing Date	Batch No.	Examiner	Art Unit
09/887,791	June 22, 2001		Ahmed	1746-1165

Invention: FOCUSED ION BEAM PROCESS FOR REMOVAL OF COPPER



Address to:  
Assistant Commissioner for Patents  
Washington, D.C. 20231

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TC 1700

Transmitted herewith are:

two (2) sheets of formal drawing(s) for this application.

Each sheet of drawing indicates the identifying indicia suggested in 37 CFR Section 1.84(c)  
on the reverse side of the drawing.

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Signature

Peter R. Hagerty  
Registration No. 42,618  
Customer No. 23413

Dated: September 18, 2001

I certify that this document and attached formal drawings  
are being deposited on September 18, 2001 with the  
U.S. Postal Service as first class mail under 37 C.F.R. 1.8  
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Marjorie R. Humes

Signature of Person Mailing Correspondence

Marjorie R. Humes

Typed or Printed Name of Person Mailing Correspondence

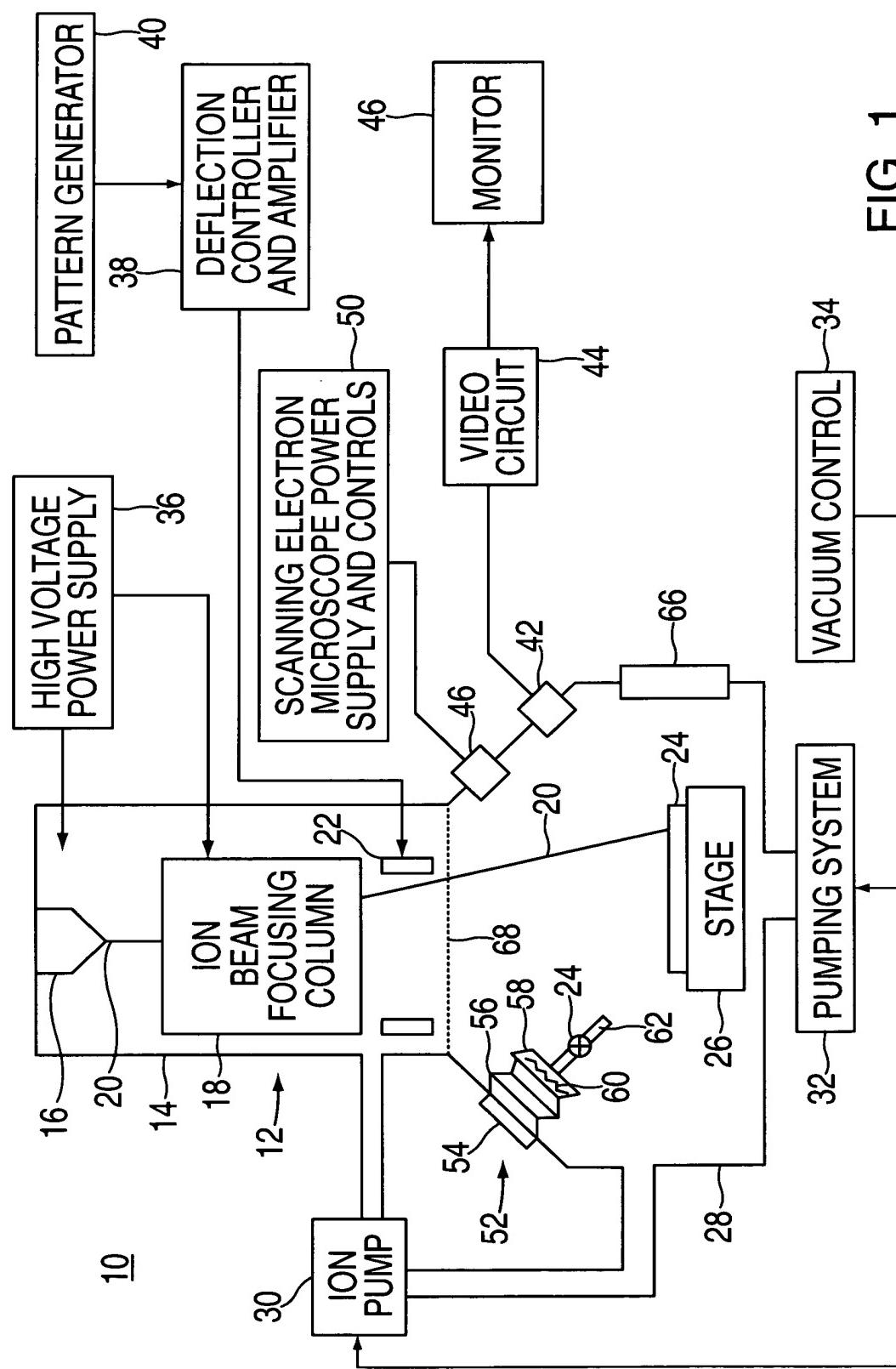


FIG. 1

FIS920000409US1(TLT)

2/2

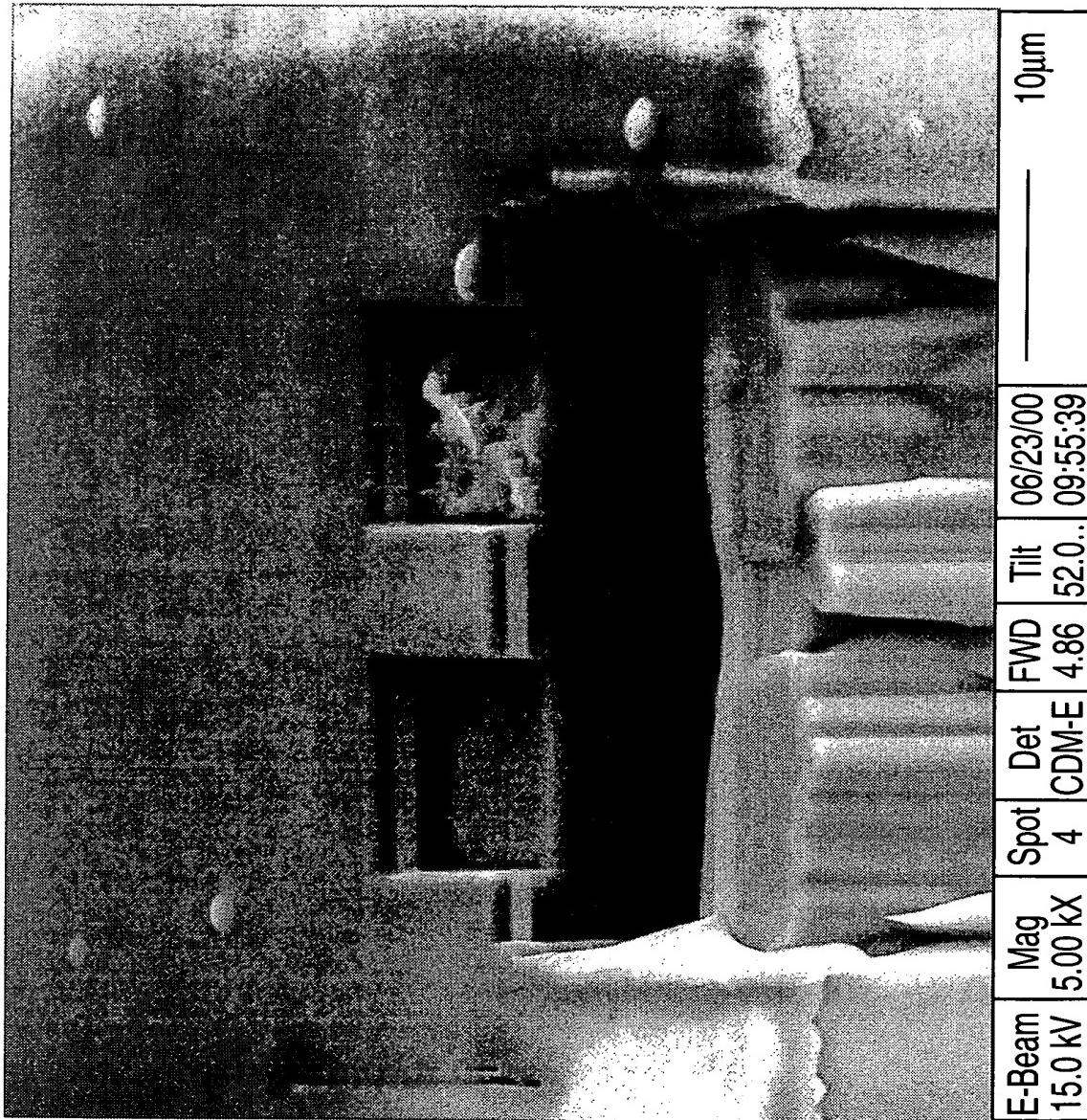


FIG. 2

E-Beam 15.0 kV	Mag 5.00 kX	Spot 4	Det CDM-E	FWD 4.86	Tilt 52.0..	06/23/00 09:55:39	10µm
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